

Claims

1. A hetero-interface field effect transistor comprising:
a substrate; and
a cation-polarity layered structure including at least a barrier layer and a channel layer wherein said barrier layer includes $\text{In}_x\text{Al}_{1-x}\text{N}$, x being in the range of about $0 \leq x \leq 0.30$.
2. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes $\text{In}_{0.17}\text{Al}_{0.83}\text{N}$
3. The hetero-interface field-effect transistor according to claim 2 wherein said channel layer includes GaN
4. The hetero-interface field-effect transistor according to claim 2 wherein said channel layer includes $\text{In}_y\text{Ga}_{1-y}\text{N}$, y being in the range of about $0 < y \leq 1$.
5. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes $\text{In}_x\text{Al}_{1-x}\text{N}$, x being in the range of about $0 \leq x < 0.17$.
6. The hetero-interface field-effect transistor according to claim 5 wherein said channel layer includes GaN
7. The hetero-interface field-effect transistor according to claim 5 wherein said channel layer includes $\text{In}_y\text{Ga}_{1-y}\text{N}$ ($0 < y \leq 1$).
8. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes $\text{In}_x\text{Al}_{1-x}\text{N}$, x being in the range of about $0.17 < x \leq 0.25$
9. The hetero-interface field-effect transistor according to claim 8 wherein said channel layer includes GaN.
10. The hetero-interface field-effect transistor according to claim 8 wherein said channel layer includes $\text{In}_y\text{Ga}_{1-y}\text{N}$, y being in the range of about $0 < y \leq 1$.

11. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes $\text{In}_x\text{Al}_{1-x}\text{N}$, x being in the range of about $0.25 < x \leq 0.30$.

12. The hetero-interface field-effect transistor according to claim 11 wherein said channel layer includes $\text{In}_y\text{Ga}_{1-y}\text{N}$, y being in the range of about $0 < y \leq 1$.

13. A hetero-interface field effect transistor comprising:
a substrate; and
a layered QW structure including at least a barrier layer and a channel layer providing the total two dimensional electron gas density of above $n_{\text{total}} = 1.1 \times 10^{13} \text{ cm}^{-2}$.

14. A portable telephone phone comprising the hetero-interface field effect transistor of claim 1 or 13.

15. A communication system comprising the hetero-interface field effect transistor of claim 1 or 13.

16. A low noise amplifier comprising the hetero-interface field effect transistor of claim 1 or 13.

17. A radar system comprising the hetero-interface field effect transistor of claim 1 or 13.

18. A sensor comprising the hetero-interface field effect transistor of claim 1 or 13.

19. An intermediate frequency amplifier comprising the hetero-interface field effect transistor of claim 1 or 13.

20. A direct broadcast satellite system comprising the hetero-interface field effect transistor of claim 1 or 13.

21. A satellite communication system comprising the hetero-interface field effect transistor of claim 1 or 13.

22. A method for fabricating a hetero-interface field effect transistor comprising:
providing a substrate; and
fabricating a layered QW structure including at least a barrier layer and a channel layer providing the total two dimensional electron gas density of above $n_{\text{total}} = 1.1 \times 10^{13} \text{ cm}^{-2}$.

23. A method for fabricating a hetero-interface field effect transistor comprising:
providing a substrate; and
fabricating a layered QW structure including at least a barrier layer and a channel layer wherein barrier layer includes $\text{In}_x\text{Al}_{1-x}\text{N}$ where $0 \leq x \leq 0.30$.

24. A method using a hetero-interface field effect transistor in a communications system comprising:
(a) fabricating the hetero-interface field effect transistor using the steps of:
providing a substrate; and
fabricating a layered QW structure including at least a barrier layer and a channel layer wherein barrier layer includes $\text{In}_x\text{Al}_{1-x}\text{N}$ where $0 \leq x \leq 0.30$; and
(b) using the fabricated hetero-interface field effect transistor in the communications system.

25. A method using a hetero-interface field effect transistor in an electronic device comprising an electronic circuit including a hetero-interface field effect transistor using having a substrate; and a layered quantum well structure including at least a barrier layer and a channel layer providing a polarization-induced charge.

26. An electronic device utilizing a hetero-interface field effect transistor comprising a substrate, and a layered quantum well structure including at least a barrier layer and a channel layer providing a polarization-induced charge.

27. The hetero-interface field-effect transistor according to claim 26 wherein said channel layer includes GaN.

28. The hetero-interface field-effect transistor according to claim 26 wherein said channel layer includes $\text{In}_y\text{Ga}_{1-y}\text{N}$, y being in the range of about $0 < y \leq 1$.

29. The hetero-interface field-effect transistor according to claim 26 wherein said barrier layer includes $\text{In}_x\text{Al}_{1-x}\text{N}$, x being in the range of about $0 \leq x < 0.17$.

30. The hetero-interface field-effect transistor according to claim 29 wherein said channel layer includes GaN.